Abstract

Lithographic Apparatus, Device Manufacturing Method, and Device Manufactured Thereby.

A lithographic projection apparatus comprising: a radiation system for providing a projection beam of radiation; an article holder comprising a plurality of protrusions defining a protrusion configuration arranged to provide a flat plane of support for supporting a substantially flat article to be placed in a beam path of said projection beam of radiation, the article holder comprising at least one clamping electrode for generating an electrostatic clamping force, for clamping an article against the article holder. According to the invention, said at least one clamping electrode comprises an electric field changing structure for locally changing said electrostatic clamping force for leveling local height variations of said substrate.

Fig. 4